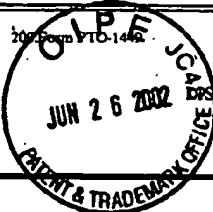


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LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Weimin Li		FILING DATE January 20, 1999	
U.S. PATENT DOCUMENTS				GROUP 2818			
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DV	AA	5,801,399	Hattori et al	257	69		
DV	AB	5,994,730	Shrivastava et al	257	306		
DV	AC	6,040,619	Wang et al	257	649		
DV	AD	6,060,765	Maeda	257	635		
DV	AE	6,060,766	Mehta et al	257	639		
DV	AF	6,133,613	Yao et al	257	437		
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EXAMINER <i>Gruland</i>				DATE CONSIDERED 02/12/02			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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DV	AA	5,482,894	01-1996	Havemann			
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EXAMINER <i>Phil</i>				DATE CONSIDERED 08/22/02			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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EXAMINER <i>Richard</i>				DATE CONSIDERED 08/12/03			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with SOC communication to applicant.							

200. Form PCT-4 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M22-1035		SERIAL NO. 09/234,233	
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FILING DATE January 20, 1999				GROUP 2818	

U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
DV	AA	5,986,318	11/1999	Kim et al			
DV	AB	6,087,064	06/2000	Lin et al			
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FOREIGN PATENT DOCUMENTS							
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EXAMINER <i>Shuland</i>	DATE CONSIDERED <i>05/27/03</i>
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

200. Form PCT/44 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1035		SERIAL NO. 09/234,233	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Weimin Li	
FILING DATE January 20, 1999				GROUP 2818	

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U.S. PATENT DOCUMENTS							
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DV	AB	6,087,064	06/2000	Lin et al			
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EXAMINER <i>Shuland</i>	DATE CONSIDERED 05/27/03
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* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

LIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)APPLICANT
Weidun Li et alFILING DATE
January 20, 1999GROUP
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U.S. PATENT DOCUMENTS

Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
DV	AA 4,775,478	07/1988	Abernathy et al			
	AB 4,870,470	09/1989	Bae et al			
	AC 5,312,768	05/1994	Gonzalez			
	AD 5,459,838	08/1995	Yang			
	AE 6,001,747	12/1999	Aampragada			
	AF 6,518,122	02/2003	Chan			
	AG 6,492,688	12/2002	Ng			
	AH 6,373,114	04/2002	Jung			
DV	AJ 2001/0019868	09/2001	Gonzalez et al			
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

DV	AR	Wells, S., "Silicon Processing for the VLSI Era." Vol. 1, pp. 189-190.
	AS	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 600; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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ATTY. DOCKET NO.
M22-4035

SERIAL NO.
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LIST OF ART CITED BY APPLICANT
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FILING DATE
January 20, 1999

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U.S. PATENT DOCUMENTS

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DV	AA	5,498,555	03/96	Lin			
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DV	AM	7201716	08/95	Japan			x	
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DV	AP	Wol, S., Silicon Process., Vol 2 48-49 and 435
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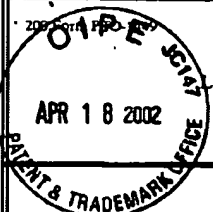
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DATE CONSIDERED 06/17/04

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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				FILING DATE January 20, 1999		
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DV	AA	6,004,850	12/99	Lucas		
	AB	6,140,677	10/00	Gardner		
	AC	6,133,096	10/00	Su		
	AD	6,136,636	10/00	Wu		
	AE	5,933,721	8/99	Hause		
	AF	5,981,368	11/99	Gardner		
	AG	6,159,804	12/00	Gardner		
	AH	6,130,168	10/00	Chu		
	AI	6,235,591	5/01	Balasubramanian		
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EXAMINER <i>gfuland</i>			DATE CONSIDERED 05/28/02			
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>						

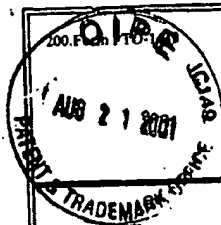
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				GROUP 2818			
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DV	AA	5,376,591	12/27/94	Macda et al			
	AB	5,817,549	10/06/98	Yamazaki et al			
	AC	6,235,568 B1	5/01	Murthy			
	AD	6,187,694 B1	2/01	Cheng			
	AE	5,750,442	5/98	Juengling			
	AF	6,114,255	9/00	Juengling			
	AG	6,238,976	5/01	Noble			
	AH	6,008,121	12/99	Yang			
	AI	5,140,390	8/92	Li			
	AJ	5,286,661	2/94	de Fresart			
	AK	6,184,151	2/01	Adair			
DV	AL	6,225,217 B1	5/01	Usami			
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<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							

		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1035		SERIAL NO. 09/234,233	
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	AD	5,872,035	02-1999	Kim			—
	AE	4,444,617	04-1984	Whitcomb			—
	AF	6,071,799	06-2000	Park et al			—
	AG	5,691,212	11-1997	Tsai et al			—
	AH	6,187,657	02-2001	Xiang et al			—
	AI	5,792,689	08-1998	Yang et al			—
DV	AJ	2001/0023051	09-2001	Rolfson			—
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EXAMINER <i>g/meland</i>				DATE CONSIDERED 05/28/02			

* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1035		SERIAL NO. 09/234,233				
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EXAMINER <i>Shuland</i>				DATE CONSIDERED <i>10/11/01</i>				
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

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ATTY. DOCKET NO.
M122-1035

SERIAL NO.
09/234,233

LIST OF ART CITED BY APPLICANT
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APPLICANT
Weimin Li

FILING DATE
January 20, 1999

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U.S. PATENT DOCUMENTS

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LIST OF ART CITED BY APPLICANT
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Weimla LJ et al.FILING DATE
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Unknown

U.S. PATENT DOCUMENTS

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DV	AA	4,474,975	10/84	Clemons et al.			
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FOREIGN PATENT DOCUMENTS

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OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

DV	AO		M. Matsura et al.; "A Highly Reliable Self-planarizing Low-k Intermetal Dielectric for Sub-quarter Micron Interconnects"; July 1997;
			pp. 31.6.1-31.6.4
DV	AP		O. Horie et al.; "Kinetics and Mechanism of the Reactions of O ₂ P with SiH ₄ , CH ₃ SiH ₃ , (CH ₃) ₂ SiH ₂ , and (CH ₃) ₃ SiH"; The Journal of Physical Chemistry, Vol. 95, No. 11, 1991; pp. 4393-4400
DV	AQ		Robert Wuthmann et al.; "Matrix Reactions of Methylsilanes and Oxygen Atoms"; The Journal of Physical Chemistry, Vol. 92, No. 3, 1988; pp. 594-602
DV	AR		Ajay M. Joshi et al.; "Plasma Deposited Organosilicon Hydride Network Polymers as Versatile Resists for Entirely Dry Mid-Deep UV Photolithography"; SPIE Vol. 1925, 1993; pp. 709-720

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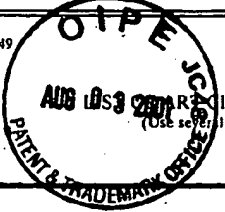
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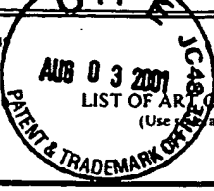
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1035		SERIAL NO. 09/234,233	
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U.S. PATENT DOCUMENTS							
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	AE	6,022,404	2/2000	Ettlinger et al	—	—	—
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	AG	4,648,904	3/1987	Depasquale et al	—	—	—
	AH	4,158,717	6/1979	Nelson	—	—	—
	AI	5,667,015	9/1997	Harestad et al	—	—	—
	AJ	5,661,093	8/1997	Ravi et al	—	—	—
	AK	5,536,857	7/1996	Naula	—	—	—
	AL	4,695,859	9/1987	Guha et al	—	—	—
	AM	4,954,867	6/1990	Hosaka	—	—	—
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	AO	5,710,067	1/1998	Foote	—	—	—
	AP	5,759,755	6/1998	Park et al	—	—	—
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EXAMINER <i>Shuland</i>				DATE CONSIDERED <i>10/11/01</i>			
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							


200 Form PTO-1449					ATTY. DOCKET NO. M122-1035		SERIAL NO. 09/234,233	
					APPLICANT Weimin Li			
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	AE	4,833,096	5/1989	Huang et al				
	AF	5,405,489	4/1995	Kim et al				
	AG	5,470,772	11/1995	Woo				
	AH	5,652,187	7/1997	Kim et al				
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DV	AN	9750993	2/1997	Japan			✓	
DV	AO	63-157443A	6/30/1988	Japan (Morita)			✓	
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
DV	AP	TEXT: Jenkins, F. et al., "Fundamentals of Optics", Properties of Light, pp. 9-10. (No date)						
DV	AO	TEXT: Wolf, S. et al., "Silicon Processing for the VLSI Era", Vol. 1, pp. 437-441. (No date)						
	AR							
EXAMINER <i>ghuland</i>				DATE CONSIDERED 10/11/01				
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>								

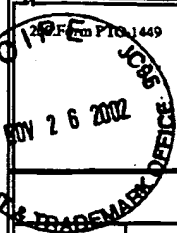
Form PTO-1449				U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1035		SERIAL NO. 09/234,233	
APPLICANT Weimin Li						FILING DATE January 20, 1999		GROUP 2818	
U.S. PATENT DOCUMENTS									
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DV	AA	5,061,509	10/1991	Naito et al					
	AB	4,600,671	7/1986	Saitoh et al					
	AC	5,753,320	5/1998	Mikoshiba et al					
	AD	5,356,515	10/1994	Tahara et al					
	AE	5,674,356	10/07/97	Nagayama					
	AF	5,731,242	03/24/98	Parat et al.					
	AG	5,741,721	04/21/98	Stevens					
	AH	5,034,348	07/23/91	Hartswick et al.					
	AI	5,472,829	12/05/95	Ogawa					
	AJ	5,641,607	06/24/97	Ogawa et al.					
DV	AK	5,648,202	07/15/97	Ogawa et al.					
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DV	AM	5-263255	10/1993	Japan				✓	
DV	AN	0 471 185 A2	7/10/91	EPO				✓	
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)									
DV	AO	D.R. McKenzie et al., "New Technology for PACVD", Surface and Coatings Technology, 82 (1996), pp. 326-333.							
DV	AP	S. McClatchie et al.; "Low Dielectric Constant Flowfill® Technology For IMD Applications"; undated; 7 pages							
DV	AQ	K. Beekmann et al.; "Sub-micron Gap Fill and In-Situ Planarisation using Flowfill™ Technology"; October 1995; pp. 1-7							
EXAMINER				DATE CONSIDERED					
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LIST OF ARTS CITED BY APPLICANT (Use separate sheets if necessary)				APPLICANT Weimin Li				
				FILING DATE January 20, 1999		GROUP 2818		
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
DV	AA	5,670,297	09/23/97	Ogawa et al.				
	AB	5,677,111	10/14/97	Ogawa				
	AC	5,698,352	12/16/97	Ogawa et al.				
	AD	5,831,321	11/03/98	Nagayama				
	AE	5,591,566	01/07/97	Ogawa				
	AF	6,008,124	12/28/99	Sekiguchi et al.				
	AG	5,340,621	08/23/94	Matsumoto et al.				
	AH	5,600,165	02/04/97	Tsukamoto et al.				
	AI	5,872,385	02/16/99	Taft et al.				
	AJ	5,960,289	09/28/99	Tsui et al.				
	AK	5,968,324	10/19/99	Cheung et al.				
DV	AL	6,020,243	02/01/00	Wallace et al.				
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DV	AM	0 588 087 A2	8/18/93	EPO				✓
DV	AN	0 588 087 A3	8/18/93	EPO				✓
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
DV	AO	A. Kiermasz et al.; "Planarisation for Sub-Micron Devices Utilising a New Chemistry"; Electrotech, February 1995; 2 pages						
DV	AP	IBM Technical Disclosure Bulletin "Low-Temperature Deposition of SiO ₂ , Si ₃ N ₄ or SiO ₂ -Si ₃ N ₄ ," Vol. 28, No. 9, p. 4170, Feb. 1986.						
DV	AQ	ARTICLE: Bencher, C. et al., "Dielectric antireflective coatings for DUV lithography", Solid State Technology (March 1997), pp.109-114.						
EXAMINER				DATE CONSIDERED				
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

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DV	AA	6,054,379	04/25/00	Yau et al.					
	AB	5,948,482	09/07/99	Brinker et al.					
	AC	5,800,877	09/01/98	Maeda et al.					
	AD	5,260,600	11/09/93	Harada					
	AE	4,992,306	02/12/91	Hochberg et al.					
	AF	4,702,936	10/27/87	Maeda et al.					
	AG	4,863,755	09/05/89	Hess et al.					
	AH	5,234,869	08/10/93	Mikata et al.					
	AI	5,302,366	04/12/94	Schuetz et al.					
	AJ	5,591,494	01/07/97	Sato et al.					
	AK	5,968,611	10/19/99	Kaloyeros et al.					
	AL	6,159,871	12/12/00	Loboda et al.					
	AM	5,744,399	4/1998	Rostoker					
	AN	5,883,014	3/1999	Chen					
DV	AO	6,017,779	1/25/00	Miyasaka					
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DV	AP	09055351	25/2/97	Japan					
DV	AQ	0 778 496 A2	05/12/96	EPO					
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)									
DV	AR	Noboru Shibata, "Plasma-Chemical Vapor-Deposited Silicon Oxide/Silicon Oxynitride Double-Layer Antireflective Coating for Solar Cells", Japanese Journal of Applied Physics, Vol. 30, No. 5, May 1991, pp. 997-1001.							
DV	AS	Julius Grant, Hackb's Chemical Dictionary, Fourth Edition, McGraw-Hill Book Company, © 1969, rented by Grant © 1972, pp. 27.							
EXAMINER				DATE CONSIDERED					
Schulard				10/11/01					
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>									

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	AB	6,156,674	12/5/00	Li et al	—	—	—		
	AC	6,461,003	10/24/95	Haveman	—	—	—		
	AD	6,124,641	9/26/00	Matsura	—	—	—		
	AE	5,554,567	9/10/96	Wang	—	—	—		
DV	AF	6,028,015	2/22/00	Wang	—	—	—		
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DV	AG	EP 0 464 515 A3/B1	08.01.92	EPO (Mikata et al.)	—	—	✓		
DV	AH	EP 0 771 886 A1	07.05.97	EPO (Loboda)	—	—	✓		
DV	AI	20029	US99	Search Report	—	—	✓		
DV	AJ	20030	US99	Search Report	—	—	✓		
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)									
DV	AK	Ralls, Kenneth M., "Introduction to Materials Science and Engineering", John Wiley & Sons, © 1976, pp. 312-313							
DV	AL	Ravi K. Laxan. "Synthesizing Low-k CVD Materials for Fab Use", Semiconductor International, Nov. 2000, 10 pps.							
DV	AM	Anonymous, "New gas helps make faster IC's, Machine Design Cleveland, © Penton Media, Inc., November 4, 1999, pp. 118							
DV	AN	Lobada et al, "Using Trimethylsilane to Improve Safety Throughput and Versatility in PECVD Processes", 4th International Symposium on Silicon Nitride and Silicon Dioxide Thin Insulating Films, The Electrochemical Society, Abstract No. 358, p. 454, May 1997.							
DV	AO	ARTICLE: Bencher, C. et al., "Dielectric antireflective coatings for DUV lithography", Solid State Technology (March 1997), pp. 109-114.							
DV	AP	ARTICLE: Dammel, R. R. et al., "Dependence of Optical Constants of AZ® BARLi™ Bottom Coating on Back Conditions", SPIE Vol. 3049 (1997), pp. 963-973.							
DV	AQ	TEXT: Heavens, O. S., "Optical Properties of Thin Solid Films", pp. 48-49.							
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.									

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DV	AB	09/146,843	9/3/98	Li et al				
DV	AC	09/030,618	2/25/98	Holscher et al				
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EXAMINER <i>gfurand</i>				DATE CONSIDERED <i>10/11/01</i>				
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U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
DV	AA	6,184,158	02/2002	Shufflebotham et al				
	AB	6,096,656	08/2000	Matzke et al				
	AC	6,209,484	04/2001	Huang et al				
	AD	6,440,860	08/2002	DeBoer et al				
	AE	5,413,963	05/1995	Yen et al				
	AF	6,143,670	11/2000	Cheng et al				
	AG	6,403,464	06/2002	Chang				
	AH	2001/0038919 A1	11/2001	Berry, III et al				
	AI	2002/0033486 A1	03/2002	Kim et al				
DV	AJ	2002/0081834 A1	06/2002	Daniels et al				
	AK							
	AL							
FOREIGN PATENT DOCUMENTS								
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DV	AM	EP 1172845 A2	01/2002	EP				✓
	AN	JP 08-213386 A	08/1996	JP				✓
	AO	JP 2000068261 A	03/2000	JP				✓
	AP	TW 368687 A	09/1999	TW				✓
	AQ	TW 429473 A	04/2001	TW				✓
DV	AR	TW 420844 A	02/2001	TW				✓
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
	AS							
	AT							
EXAMINER <i>gfuehnd</i>				DATE CONSIDERED 01/15/03				
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Sheet 1 of 1

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LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Weimin Li			
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U.S. PATENT DOCUMENTS							
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	AB						
	AC						
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	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
FOREIGN PATENT DOCUMENTS							
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	AL						
	AM						
	AN						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
Dh	AO	Wolf et al, Silicon Processing for the VLSI Era, 1986, Lattice Press, Vol. 1, pp. 1 and 2.					
	AP						
	AO						
EXAMINER		Dh		DATE CONSIDERED			
				7/2005			
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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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FOREIGN PATENT DOCUMENTS							
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	AP						
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EXAMINER Dle				DATE CONSIDERED 7/2005			
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